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PATENT ✓

Customer No. 22,852
Attorney Docket No. 08038.0032

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
)
Takayuki NIUYA et al.) Group Art Unit: 2823
)
Application No.: 09/658,193) Examiner: J. J. MALDONADO
)
Filed: September 8, 2000)
)
For: METHOD AND APPARATUS FOR)
PRODUCING SEMICONDUCTOR)
DEVICE)

Assistant Commissioner for Patents
Washington, DC 20231

Sir:

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TECHNOLOGY CENTER 2800

AMENDMENT

In reply to the Office Action dated May 13, 2002, the period for reply having been extended for three months by a request for extension and fee payment filed concurrently herewith, please amend the application as follows:

IN THE CLAIMS:

Please amend claims 11, 14, 16, and 21, as follows:

11. (Amended) A method of manufacturing a semiconductor device, comprising the steps of:
- making a first concavity in a first insulating film of the device;
 - covering the first concavity with a first barrier layer for preventing metal diffusion;
 - burying the first concavity covered with the first barrier layer with a wiring metal;

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